



Structuring and Fabrication of Sensors Based on LTCC (Low Temperature Co-fired Ceramic) Technology

<u>Hansu Birol</u>, Thomas Maeder, Caroline Jacq, Giancarlo Corradini, Marc Boers, Ingo Nadzeyka, Sigfrid Straessler & Peter Ryser

Swiss Federal Institute of Technology, Lausanne - EPFL Laboratory for Production of Microtechnologies - LPM Thick-film Group

lpmwww.epfl.ch



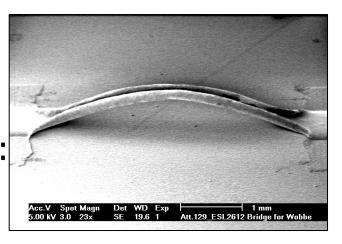




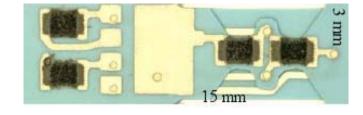
Introduction to LTCC Technology:

General aspects
Sensor applications

Fabrication techniques for sensors: *Major problems encountered Methods for structuring Methods for reducing deformation*



Fabricated sensors: Completed devices









LTCC for Wireless Applications

Base Station Amplifier Modules

Transmitters and Receivers

Handset Power Amplifiers

Low Noise Amplifiers

Voltage Control Oscillators

Mixers

Filters

Power Splitters and Combiners

Matching Networks

LTCC in the Automotive Industry

Engine Management Systems

Gearbox Management Systems

Anti-Lock Braking Systems

Global Positioning Systems

Gas Discharge Lamp Controllers

Ignition Modules

Sensor Modules

LTCC in Military & Space Environments

Transmitters/Receivers

Phased Array Radar

Amplifiers

Filters

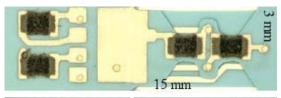
Converters

Power Drivers

Sensors

Source: C-MAC Micro-technology

And recently for ...



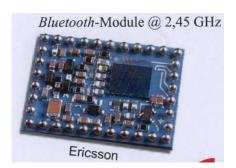






EPCOS FRONT END MODULE

Key component in new Nokia mobile phone architecture Integrates diplexer, switching, LC and SAW filters



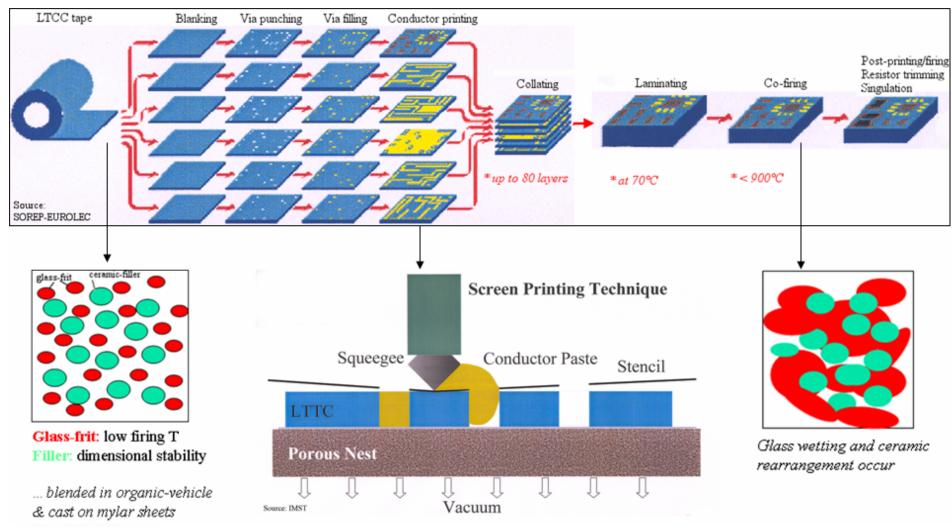
CICC-4



Introduction | F

Fabrication Devices



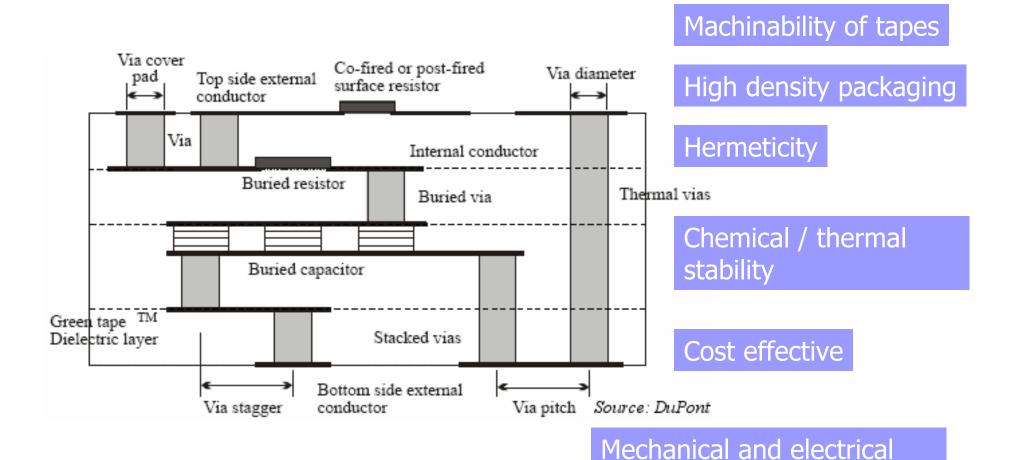




Introduction Fabrication

Devices





CICC-4

functions in one system



Fabrication

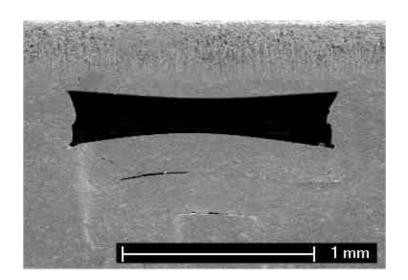
Devices



Sagging in cavities

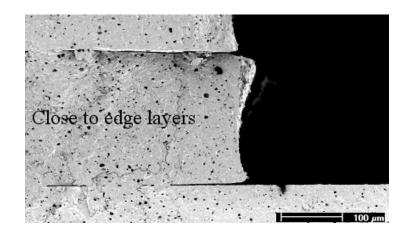
Unsupported cavity is deformed during:

- → Lamination (lamination stress)
- →Sintering (over Tg)



<u>Delamination / Disintegration</u> Occurs due to:

- → Poor lamination
- → Geometrical constraints







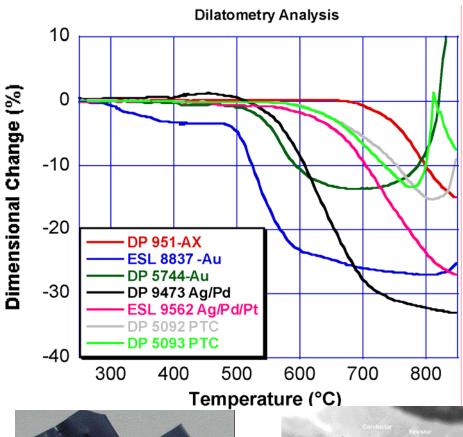
Introduction Fabrication Devices ÉCOLE POLYTECHNIQUE FÉDÉRALE DE LAUSANNE

Deformation of co-fired bodies (warpage, etc...) due to <u>differential shrinkage</u>

As a result of:

- rapid sintering
- 2. higher extent of shrinkage

of thick-film components compared to LTCC











Fabrication

Devices

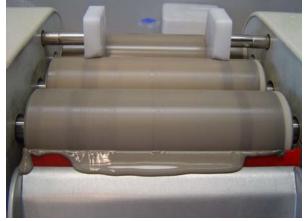


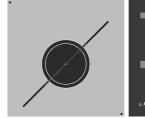
METHODS FOR STRUCTURING

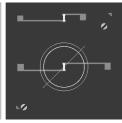
Utilization of temporary sacrificial layers, which are screen-printed & laminated with LTCC to fabricate « sag-free & well-integrated »

- micro-fluidic channels,
- cavities such as membranes,

| Product | Function | Specification | Supplier |
|--------------------|-------------|-----------------------------------|-----------------------|
| Graphite | Sacrificial | d ₅₀ : 1-2µ (used lot) | Aldrich, 28,286-3 |
| | | d ₅₀ : 11µ | KS25 |
| | | d ₅₀ : 15. 3µ | KS5-25 |
| Ethyl cellulose | Binder | control of rheology | Aldrich, 43,383-7 |
| Terpineol | Solvent | slurry viscosity | Fluka, 86480 |
| Acetyl acetone | Dispersant | dispersing additive | Sigma-Aldrich, P775-4 |











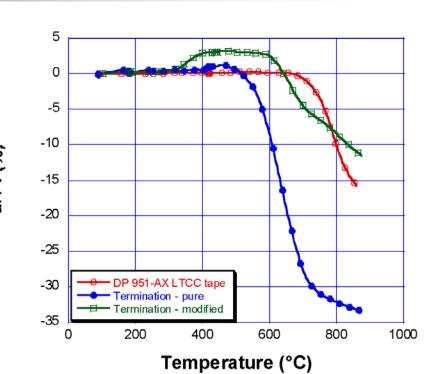
Introduction Fabrication Devices ÉCOLE PO FÉDÉRAL

METHODS FOR REDUCING

« DIFFERENTIAL SHRINKAGERELATED » DEFORMATION

Modifying commercial thickfilm components by selected additives to

- shrinkage match paste with LTCC,
- reduce the overall shrinkage of the paste,



+ 20% SiO. (wt)



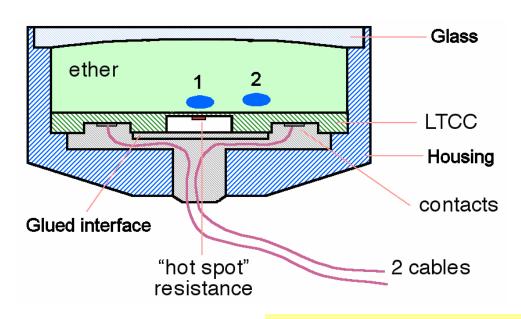


Introduction Fabrication

Devices



LTCC: an excellent substrate for hot-spot application ($\lambda \sim 2-3$ W/m.K)





PRINCIPLE

Detection of heat loss from the PTC resistor to the surroundings (bubble surface / liquid)

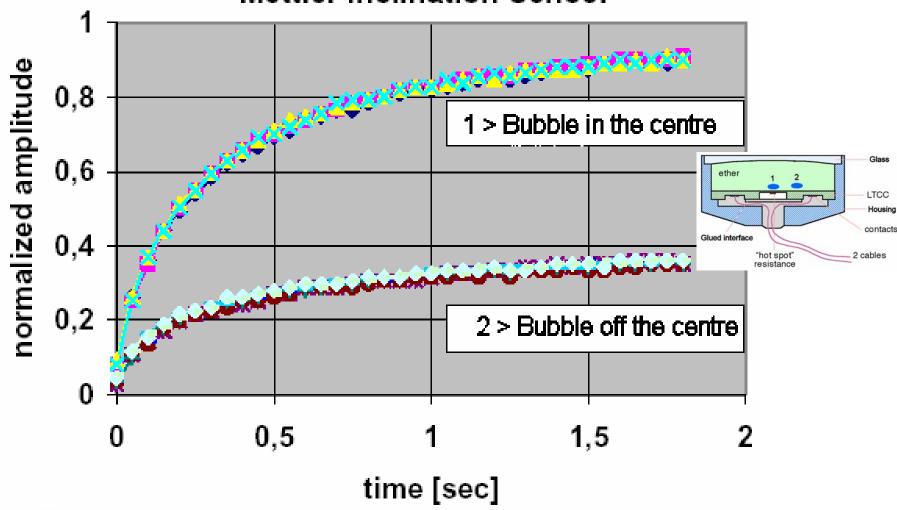








Mettler Inclination Sensor



Hansu BIROL





Fabrication

Devices



LTCC: an excellent substrate for force sensing

Maximum signal, (
$$\Delta R/R$$
) \iff Signal = $\epsilon_{max} G_f$

$$E = \sigma / \epsilon$$

Maximum strain,
$$\epsilon$$
 (Δ I/I)
$$E = \sigma / \epsilon$$

$$\sigma_{max} = (6FL) / (bh^2)$$

$$\tau = (6FL) / (bh^2)$$

| Properties | Kyocera A-476 Al ₂ O ₃ (96%) | DuPont LTCC 951 (fired) |
|--------------------------|---|-----------------------------------|
| Elastic modulus (GPa) | 330 | 152 |
| Flexural strength (MPa) | 310 | 320 |
| Available thickness (mm) | 0.25-1.00 | 0.04-0.21 |

$$\varepsilon_{LTCC} / \varepsilon_{Al2O3} = (h^2_{Al2O3} E_{Al2O3}) / (h^2_{LTCC} E_{LTCC})$$

 $\varepsilon_{LTCC}/\varepsilon_{Al2O3} \rightarrow up to \sim 70 times theoretically$



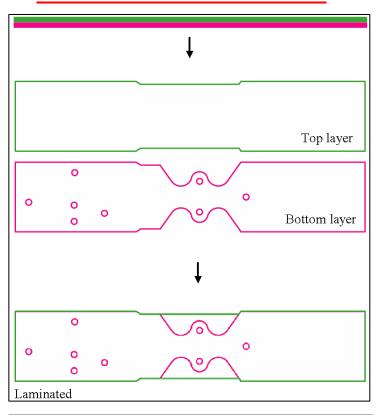


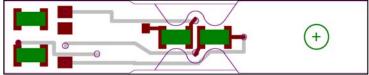
Fabrication

Devices

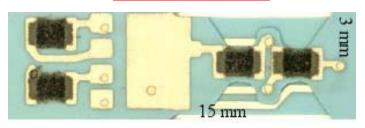


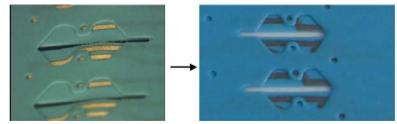
CUTTING & LAYOUT



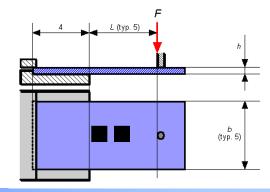


CO-FIRING





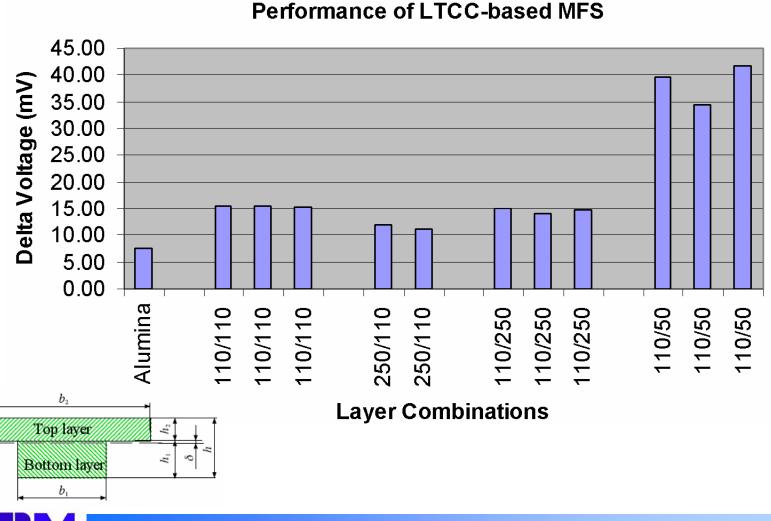
MEASUREMENT SET-UP







Introduction Fabrication Devices ÉCOLE POLYTECHNIQUE FÉDÉRALE DE LAUSANNE



plane



3. MICRO-FLUIDIC SENSOR (Pressure or heat conductivity)

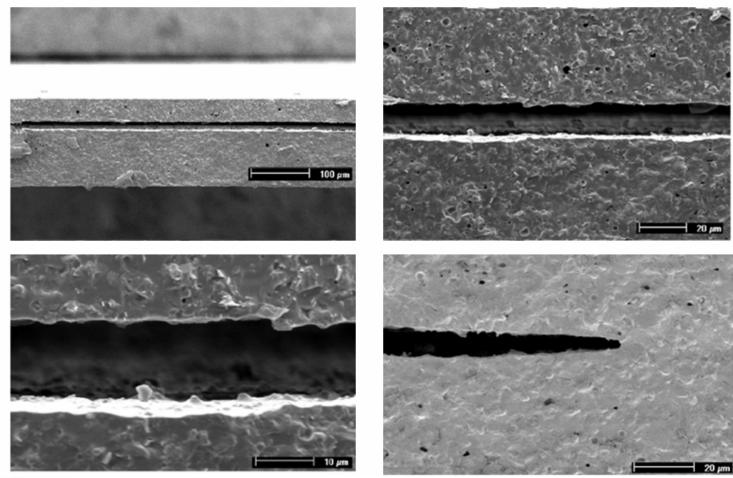
Introduction

Fabrication

Devices



LTCC + sacrificial layers: an effective & smart packaging approach





CICC-4



Fabrication

Devices



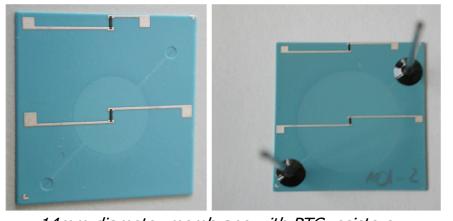
Using the graphite-based sacrificial paste, membranes produced with

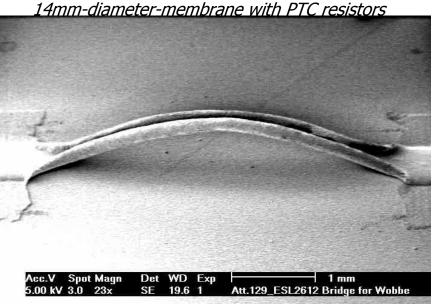
→ thickness: of 40µm

→ diameter: 7,10, 15, <u>18mm</u>

 \rightarrow spacing: (10-100µm)

Final membrane features dependent on graphite powder and LTCC properties





PTC free-hanging bridge on LTCC







→LTCC Technology has been efficiently used for fabrication of sensor & micro-fluidic devices such as:

inclination, millinewton force, pressure sensors & micro-fluidics

→Structuration & fabrication is basically limited by:

the methods used for structuring and the materials compatibility issues

→Low sintering temperature,
High packaging density,
Thermal & chemical stability
Integrability with thick-films

favors the application of the technology in multi-disciplinary areas very soon

